

# Miniature Ion Traps and Arrays for High Pressure Mass Spectrometry

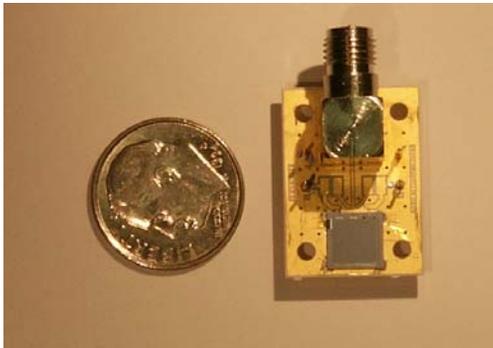
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HEMS Workshop 2005

# Progress in Miniaturization of Ion Trap Mass Spectrometry



Commercial ITMS, 45 Kg, 1800W



MGA ITMS array, 40- $\mu$ m traps

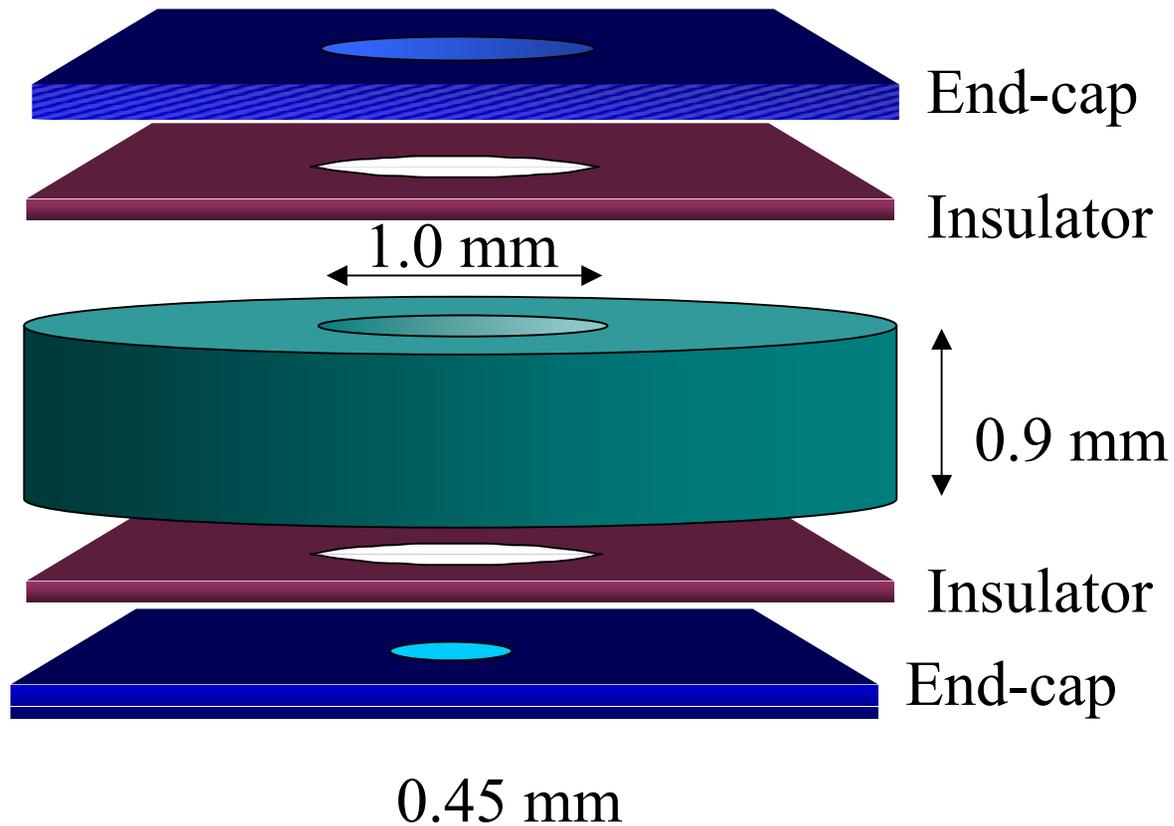


Battery-powered prototype, 10Kg, 60W

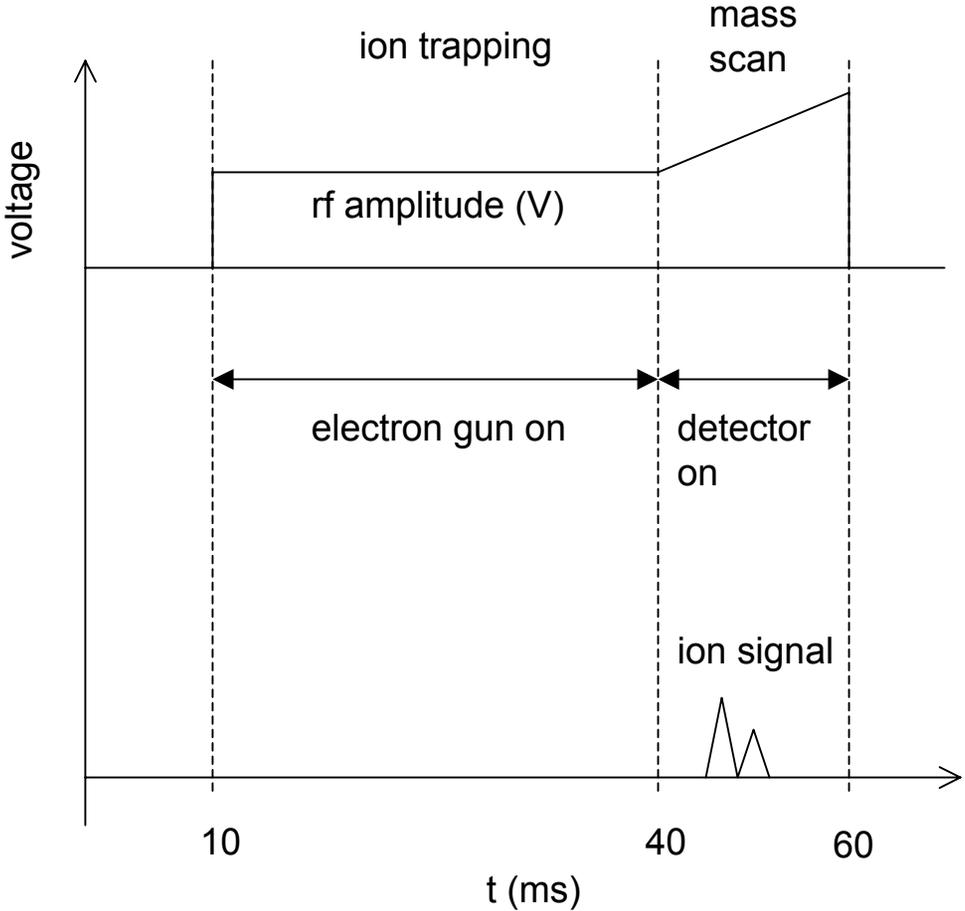
## Commercial Ion Trap Electrodes



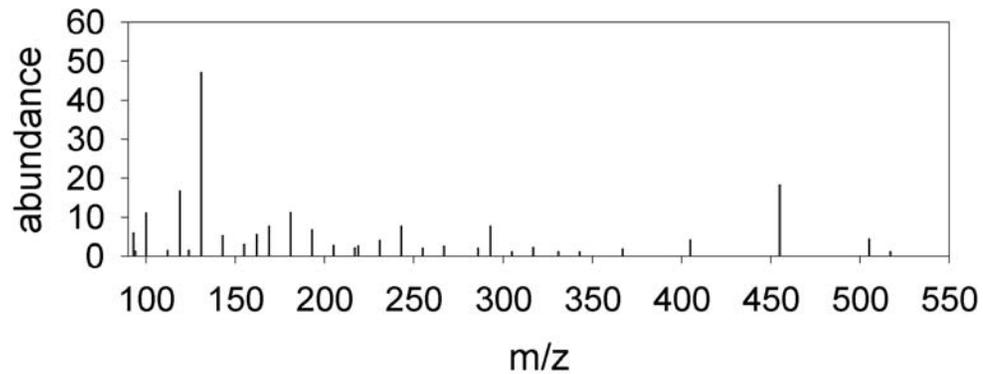
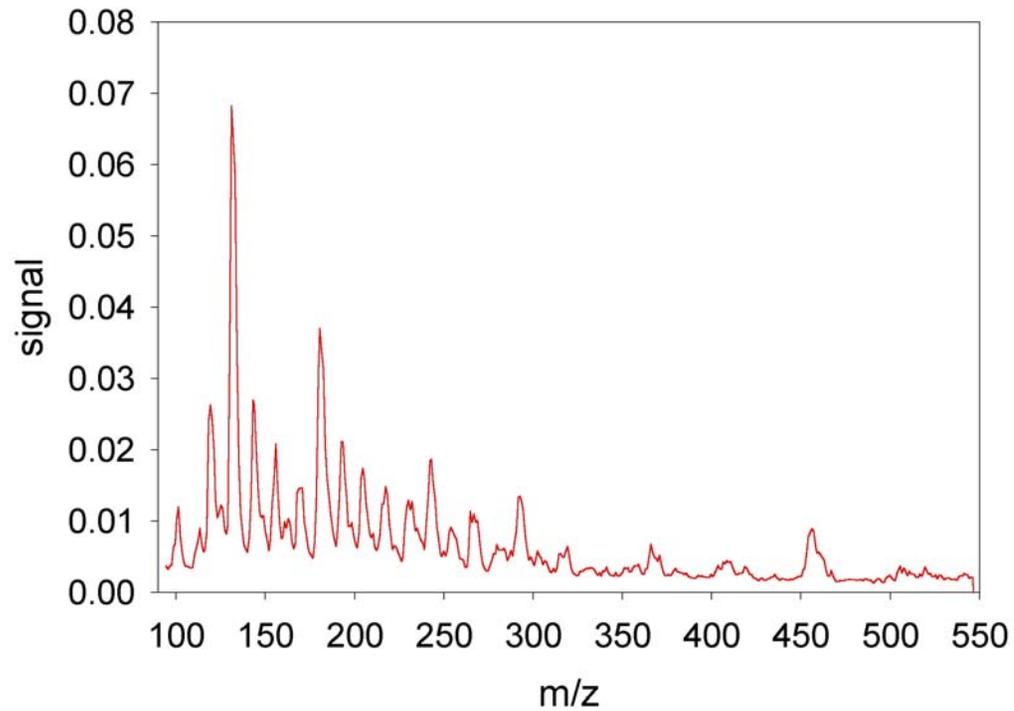
# 1-mm Cylindrical Ion Trap



# Timing sequence

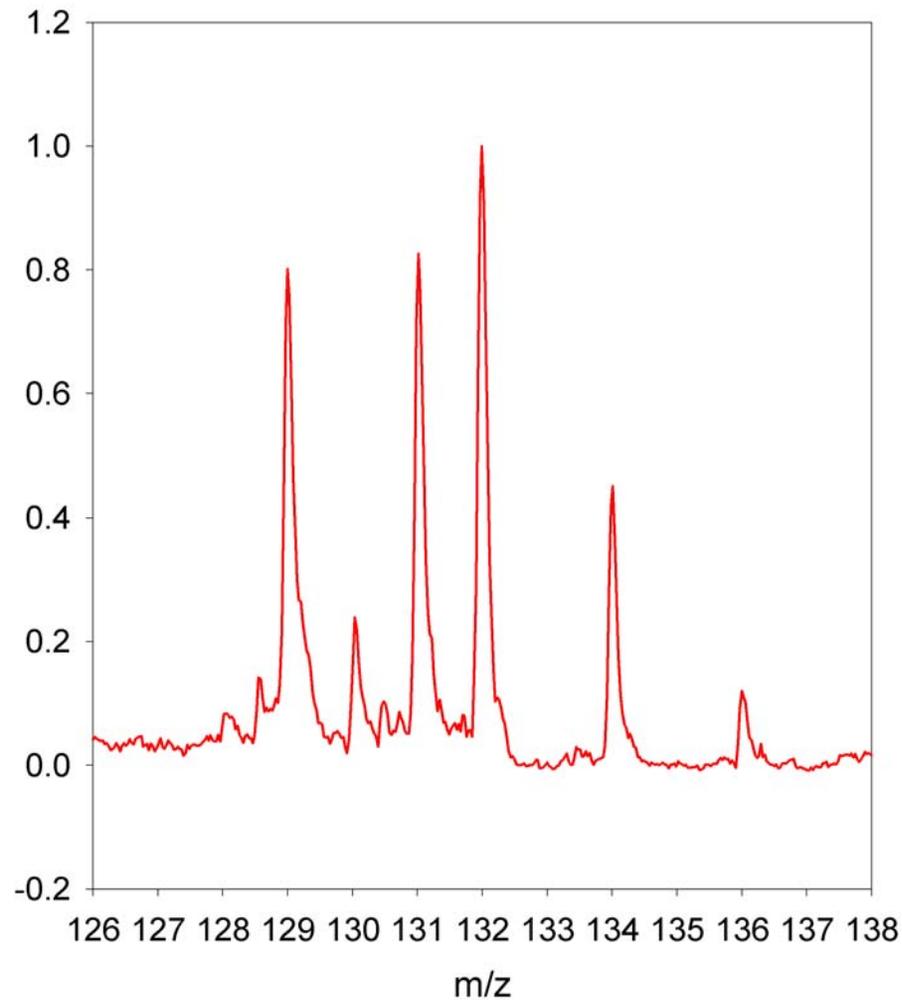


# Mass spectrum of perfluorophenanthrene



# Mass Spectrum of Xenon isotopes, 1-mm Trap

$\Omega/2\pi = 6.8$  MHz  $f_{ax} = 1.7$  MHz



The equation of motion for an ion in a quadrupole trap is

$$\frac{d^2u}{dt^2} + c \frac{du}{dt} = \frac{\alpha e}{m(r_0^2 + 2z_0^2)} [V_{DC} + V_{AC} \cos(\Omega t)] u$$

where  $\alpha = -2$  for  $u = r$ ,  $\alpha = 4$  for  $u = z$  and we have added a drag term. The velocity-dependent term can be removed by changing to a new variable,

$$u = \exp\left(-\frac{c}{2} t\right) u'$$

To put the equation in the canonical form, we also change to a dimensionless time variable,

$$\xi = \frac{\Omega t}{2}$$

giving

$$\frac{d^2 u'}{d\xi^2} + [a' - 2q' \cos 2\xi]u' = 0.$$

where

$$a' = \frac{4\alpha e}{m\Omega^2(r_o^2 + 2z_0^2)} V_{DC} - \frac{c^2}{\Omega^2} = a - \frac{c^2}{\Omega^2},$$

$$q' = \frac{2\alpha e}{m\Omega^2(r_o^2 + 2z_0^2)} V_{AC} = q,$$

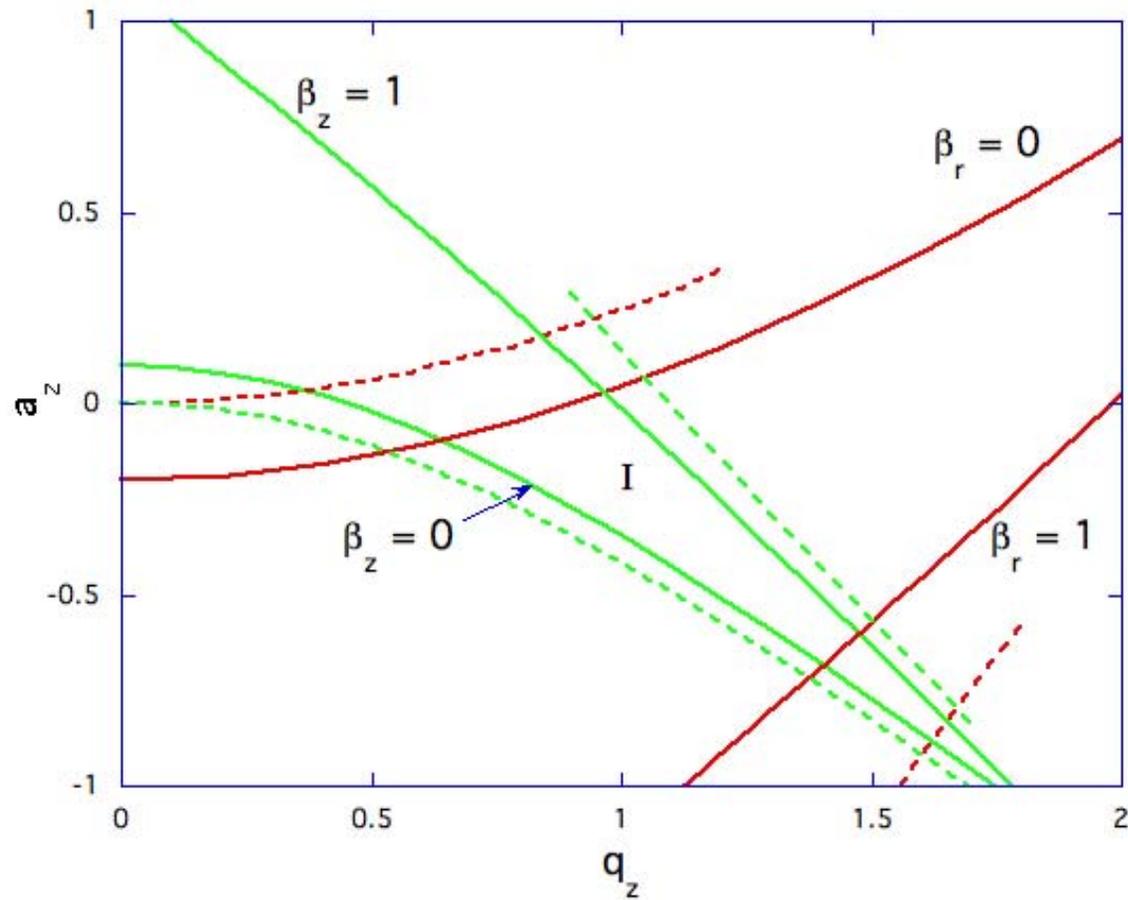
with  $\alpha = -4$  for  $u = z$  and  $\alpha = 2$  for  $u = r$ .

This reverts to the usual Mathieu equation for zero pressure,  $c = 0$ .

The only result of adding drag to the equation is to shift the value of  $a$ .



# Stability diagram for $c^2/\Omega^2 = 0.1$



How large is  $c$ ?

$c$  is given by  $2/\tau$  for oscillatory motion. Plass et. al. (*J. Phys. Chem. A* **104**, 5059-5065 (2000)) found  $\tau = 4$  ms for  $m/z$  84 at a pressure of 0.43 mTorr, giving  $c = 500$  s<sup>-1</sup>.  $c$  is linear in buffer gas pressure. At atmospheric pressure,  $c$  will be approximately  $10^9$  s<sup>-1</sup> for  $m/z$  84.

$c$  varies inversely with mass for heavy ions.

We can make  $\Omega$  as large as we want as long as the stability requirements are met.

Although not included in the analysis, we need to maintain sufficient trap depth, given approximately by  $D = q_z V_{AC}/8$ , to preclude thermal detrapping.

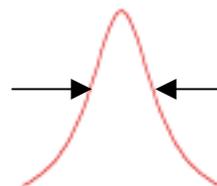
There is an uncertainty relation between collision frequency and linewidth

time dependence



$$\exp(-t/\tau)\cos(\omega_0 t)$$

frequency spectrum



$$\Delta\omega = 2(3)^{1/2}/\tau$$

$$\tau[1 + (\omega - \omega_0)^2 \tau^2]^{-1/2}$$

Goeringer et al. and Marshall et al. have shown that the linewidth resulting from collisional relaxation is given by  $\Delta\omega = 2(3)^{1/2}/\tau$ . The mass resolution will then be,

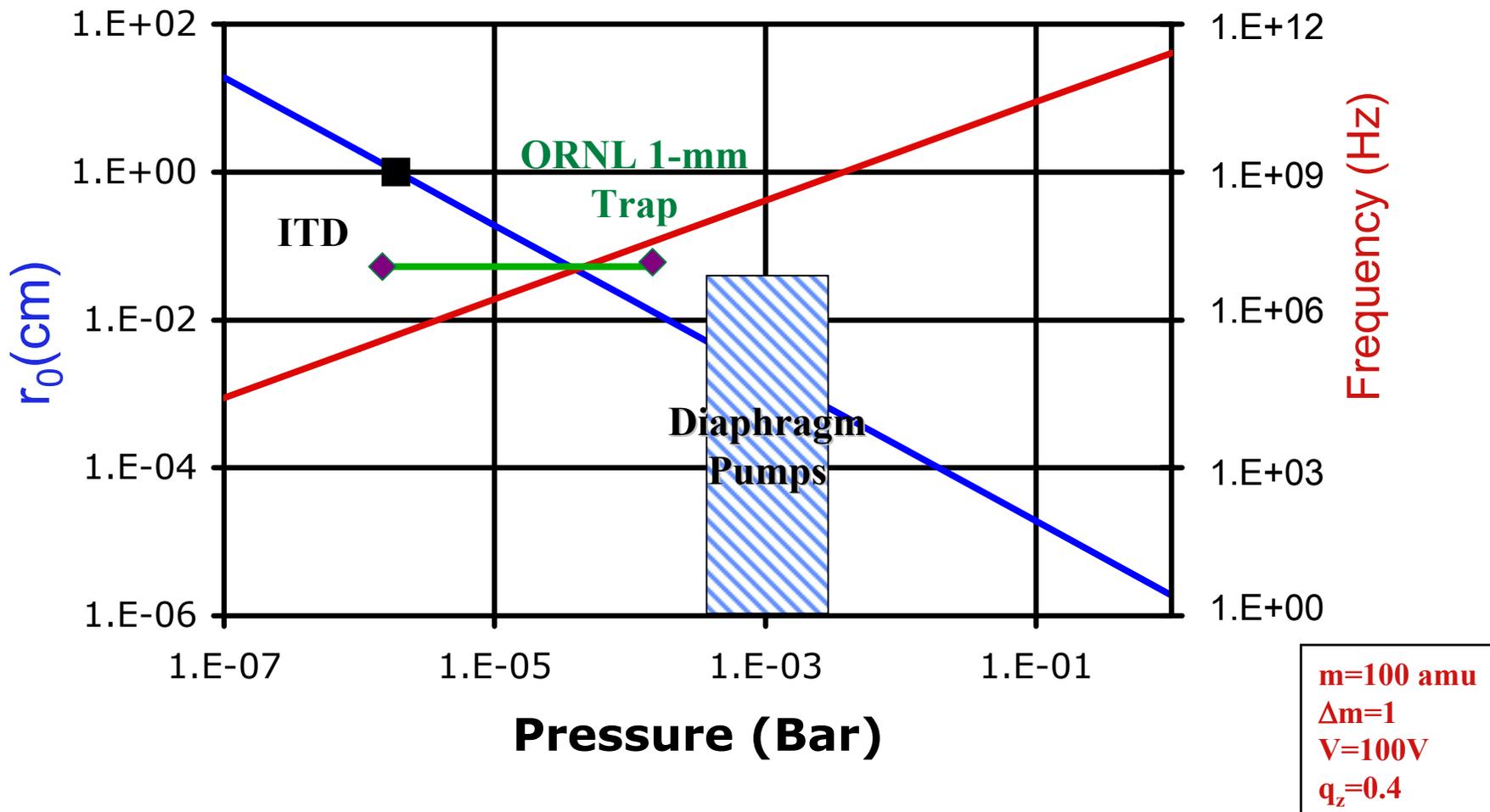
$$m/\Delta m < = \omega_0 \tau / 2(3)^{1/2} = \omega_0 / ((3)^{1/2} c)$$

Since  $c$  is proportional to the pressure, the frequency  $\omega_0$  must also increase with pressure to maintain the same resolution.

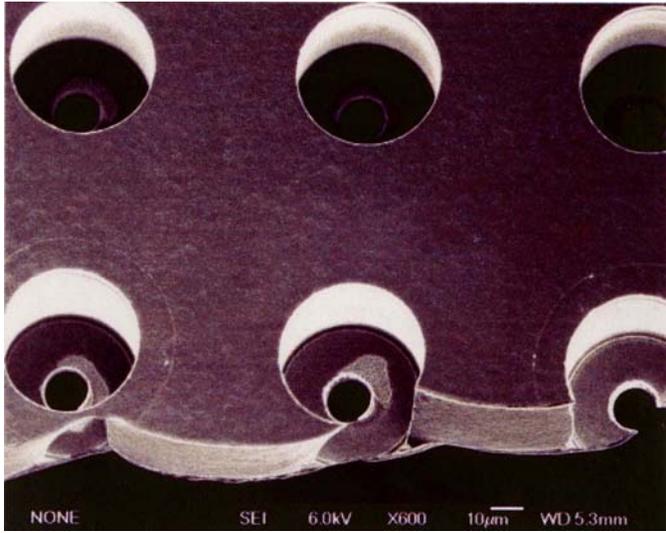
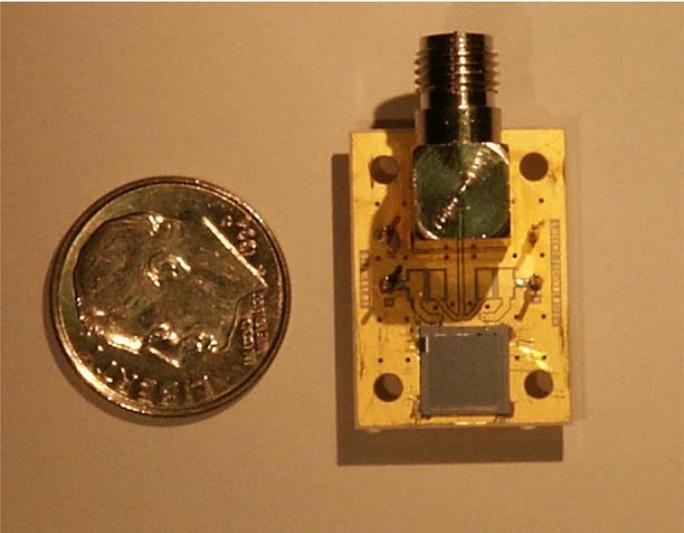
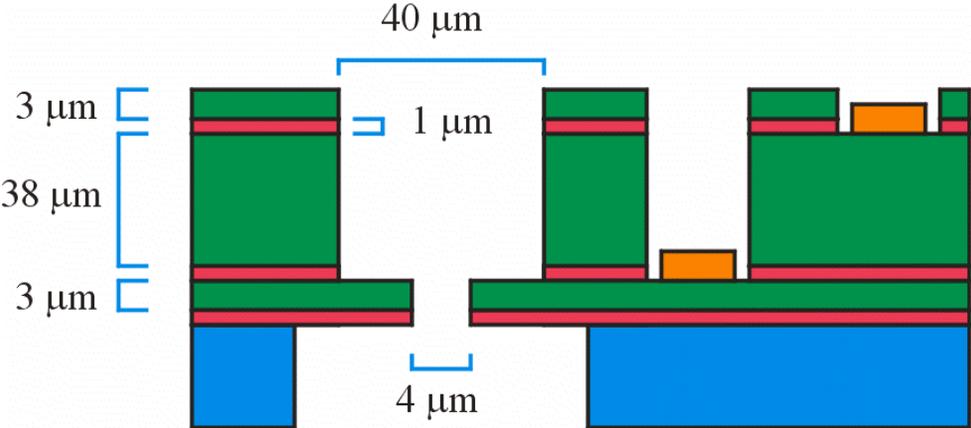
# Trap Size and Frequency vs Pressure

$$r_0 = 0.3 \times 10^{-7} \sqrt{mVq_z} \frac{\Delta m}{P}$$

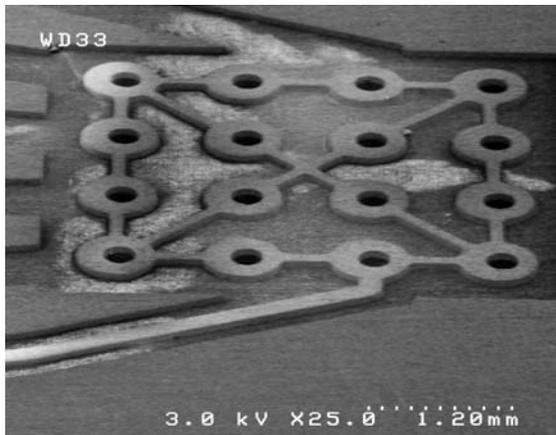
$$f = \frac{10.5 \times 10^{12} P}{q_z m \Delta m}$$



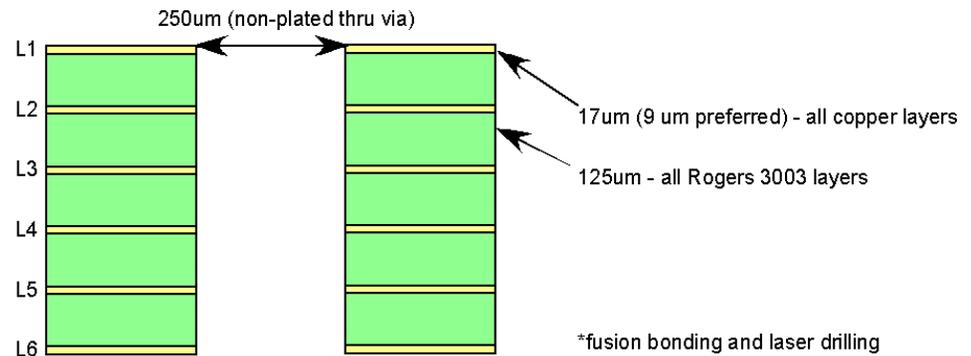
# Array of 40- $\mu\text{m}$ poly-Si ion traps fabricated at Bell Labs



Lucent has also fabricated a series of arrays of 250-mm diameter ion traps from micro circuit-board material. These arrays will be tested in both the ion drift experiment and the electron ionization experiment.

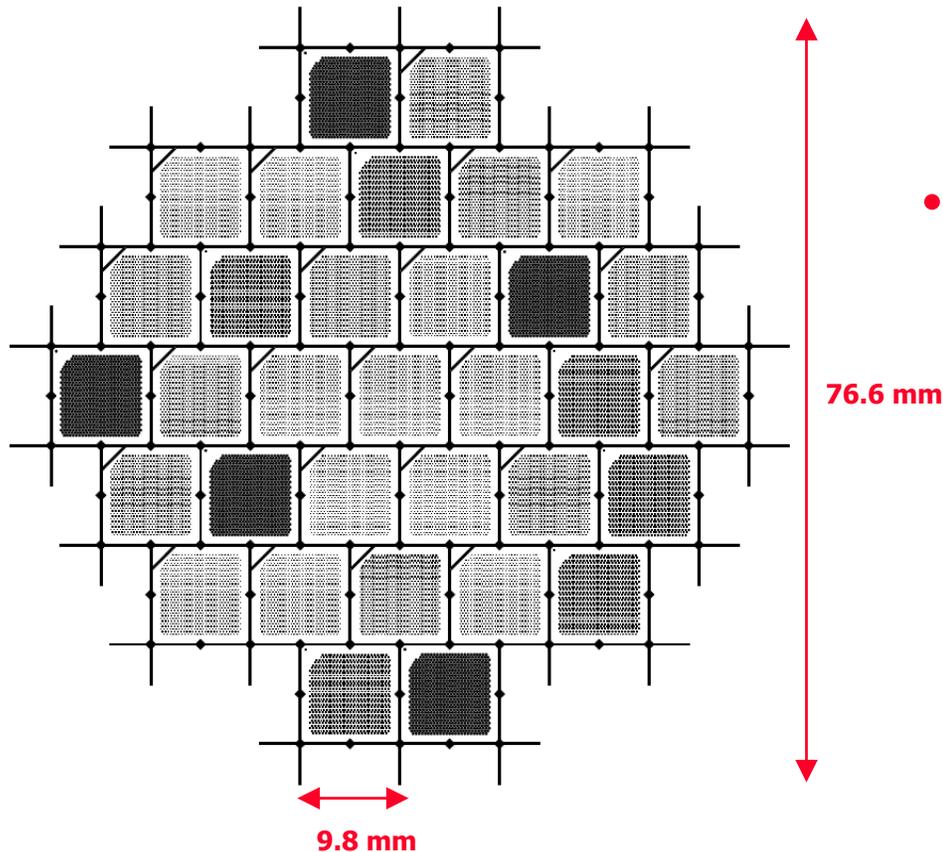


SEM image of circuit-board array



Cross-section view of each non-plated thru-via

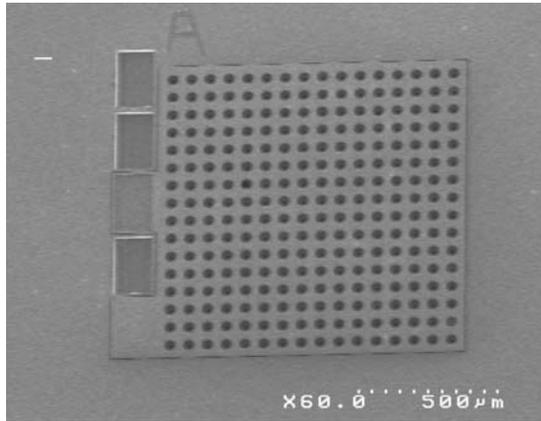
# Mask for Fabrication



- Mask contains 33 chips to fit on 4-in Silicon wafer
- Each chip has 808 holes of the same diameter
  - 5 chips have 200- $\mu\text{m}$  holes
  - 6 chips have 100- $\mu\text{m}$  holes
  - 10 chips have 60- $\mu\text{m}$  holes
  - 12 chips have 30- $\mu\text{m}$  holes

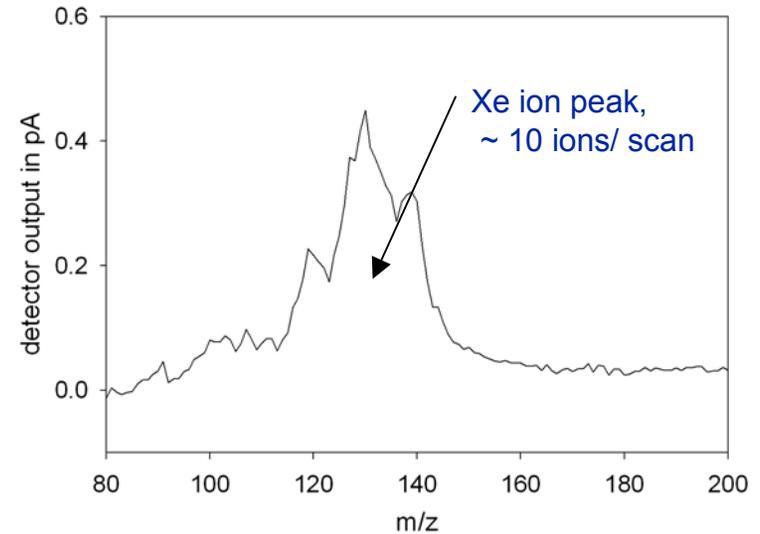
Mask for fabrication of electrode arrays

**A second generation array of 40-micrometer traps has fewer traps, lower capacitance. We can now detect trapped xenon ions at low pressure.**

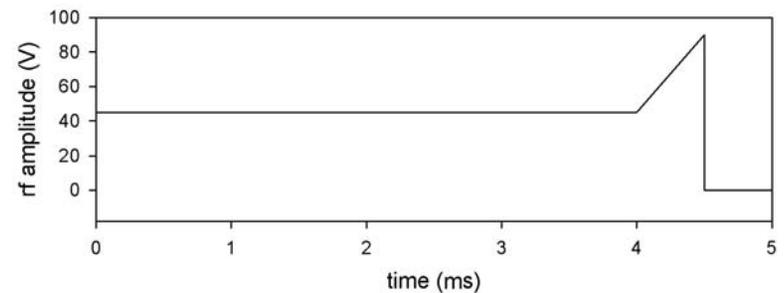


SEM image of low-capacitance array fabricated by Bell Labs

RF frequency - 100 MHz  
RF amplitude vs time at right  
Mass scan rate - 1 amu/ $\mu\text{s}$   
Multiplier gain  $\sim 10^6$  e/ion

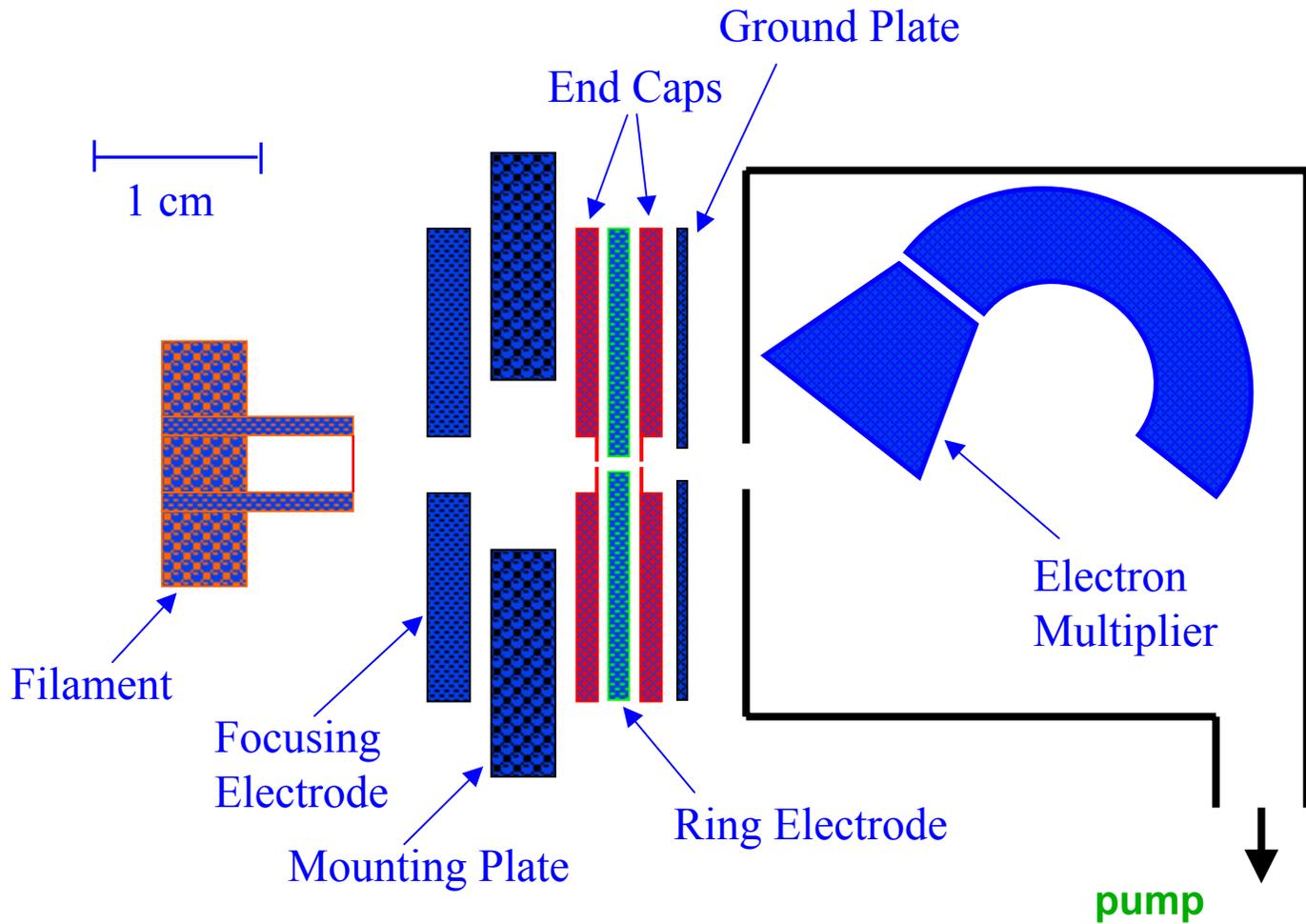


Ion signal (xenon) obtained with the array at left at low helium pressure ( $10^{-4}$  Torr) Origin at 4.090 ms.

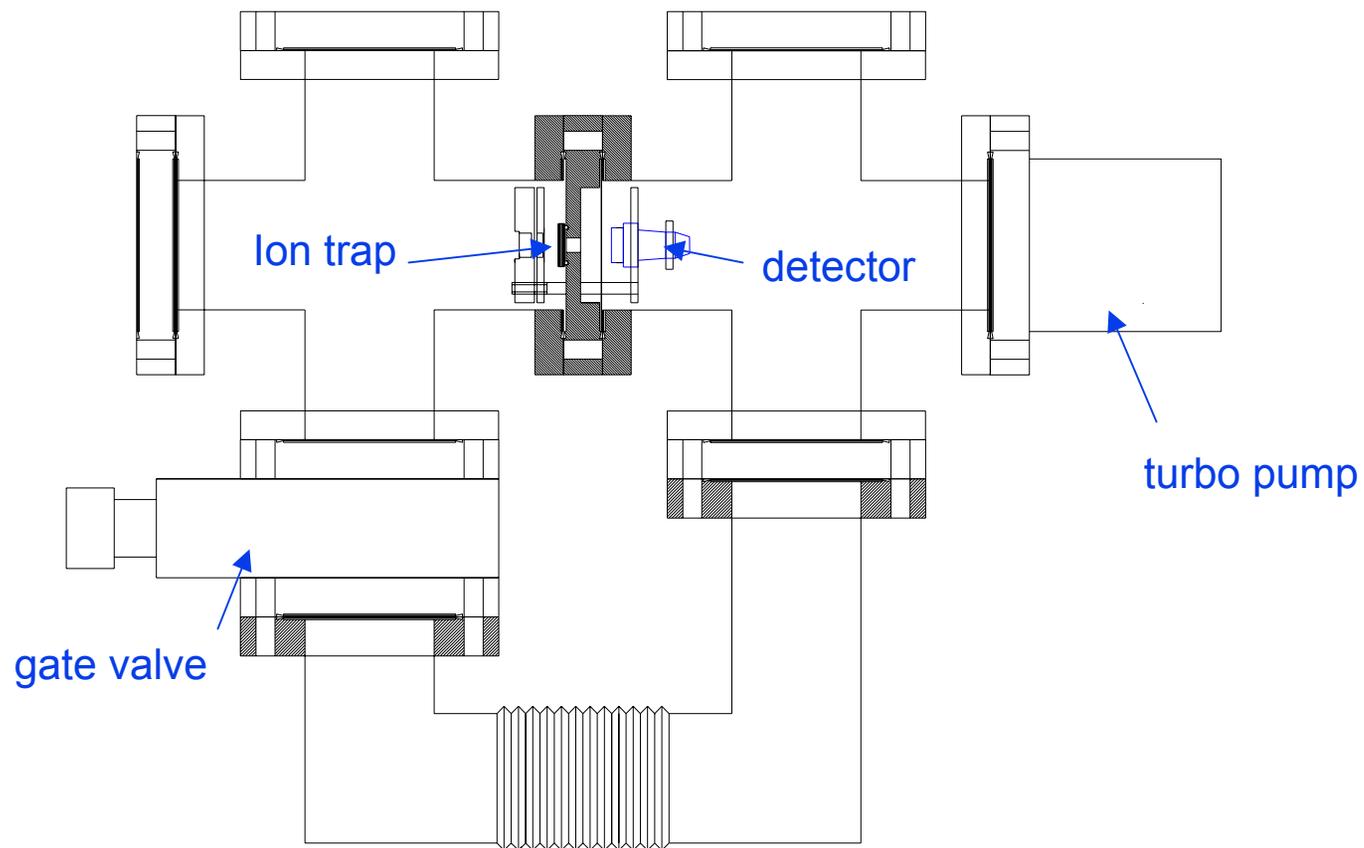


Scan function - electron gun on, 0-4 ms  
Detector on 4-5 ms

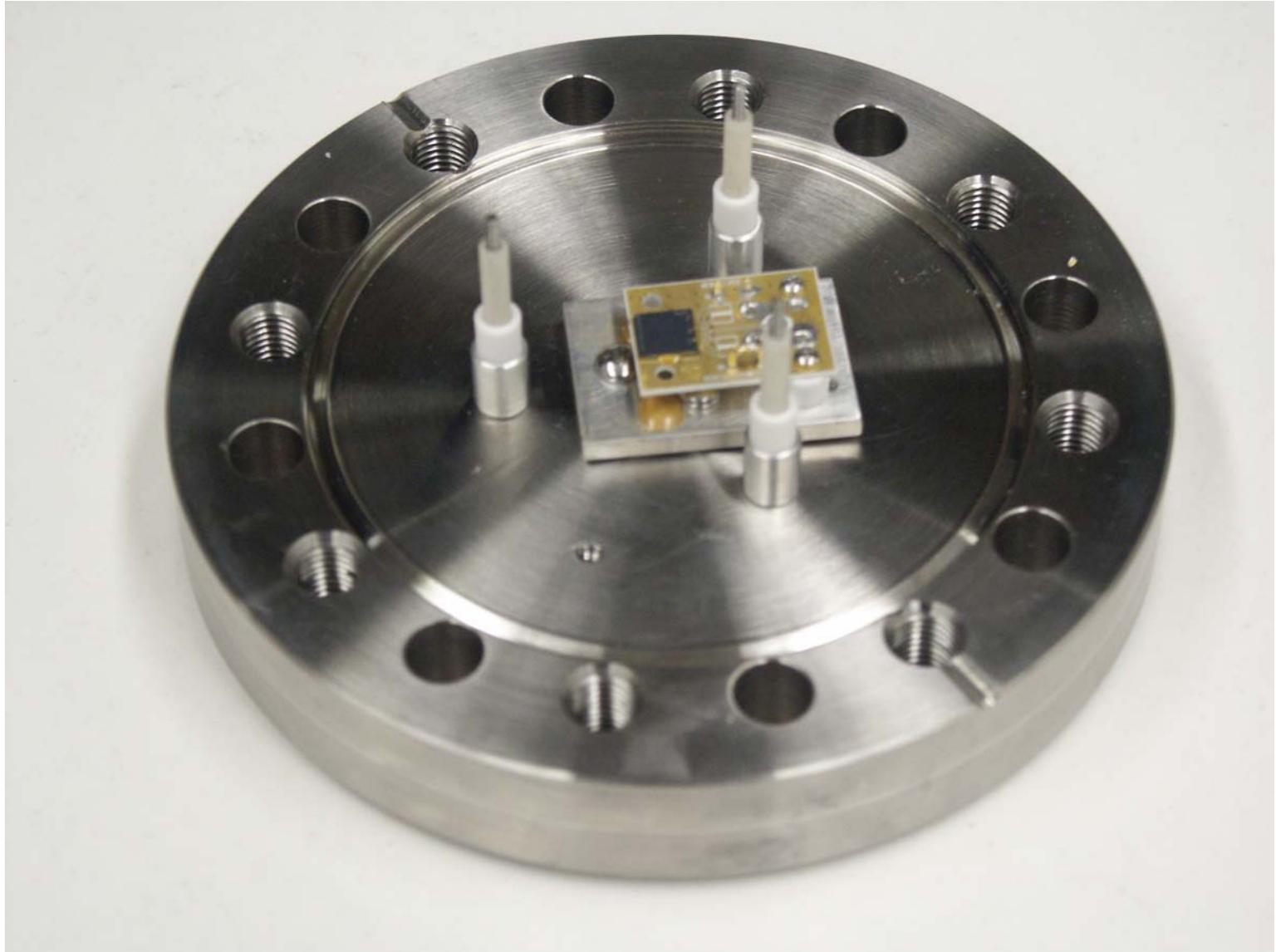
# Micro Ion Trap, Ionization Source And Detector



# Dual-chamber system for high-pressure MS



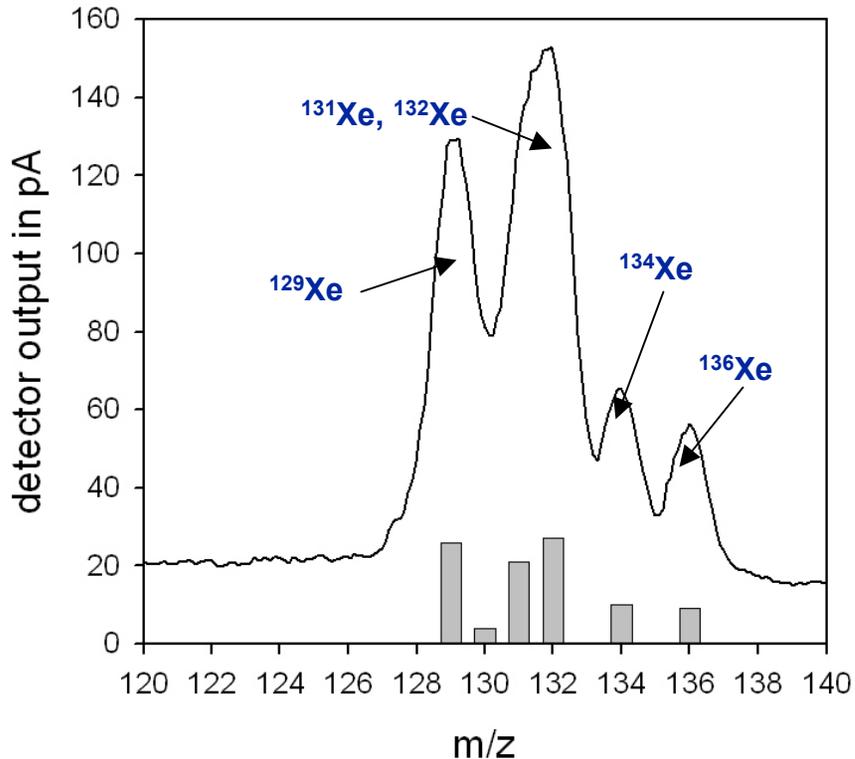
## View of mounting flange, ion trap array



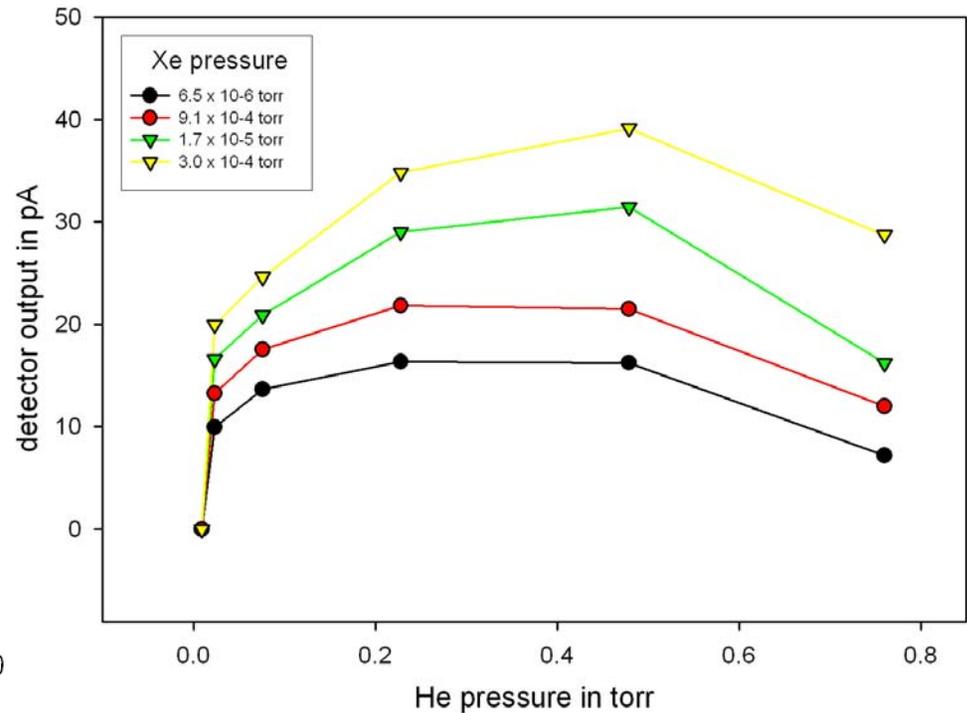
## View of detector assembly



# Experiments with a single 1-mm ion trap at high pressure, using a detector in vacuum

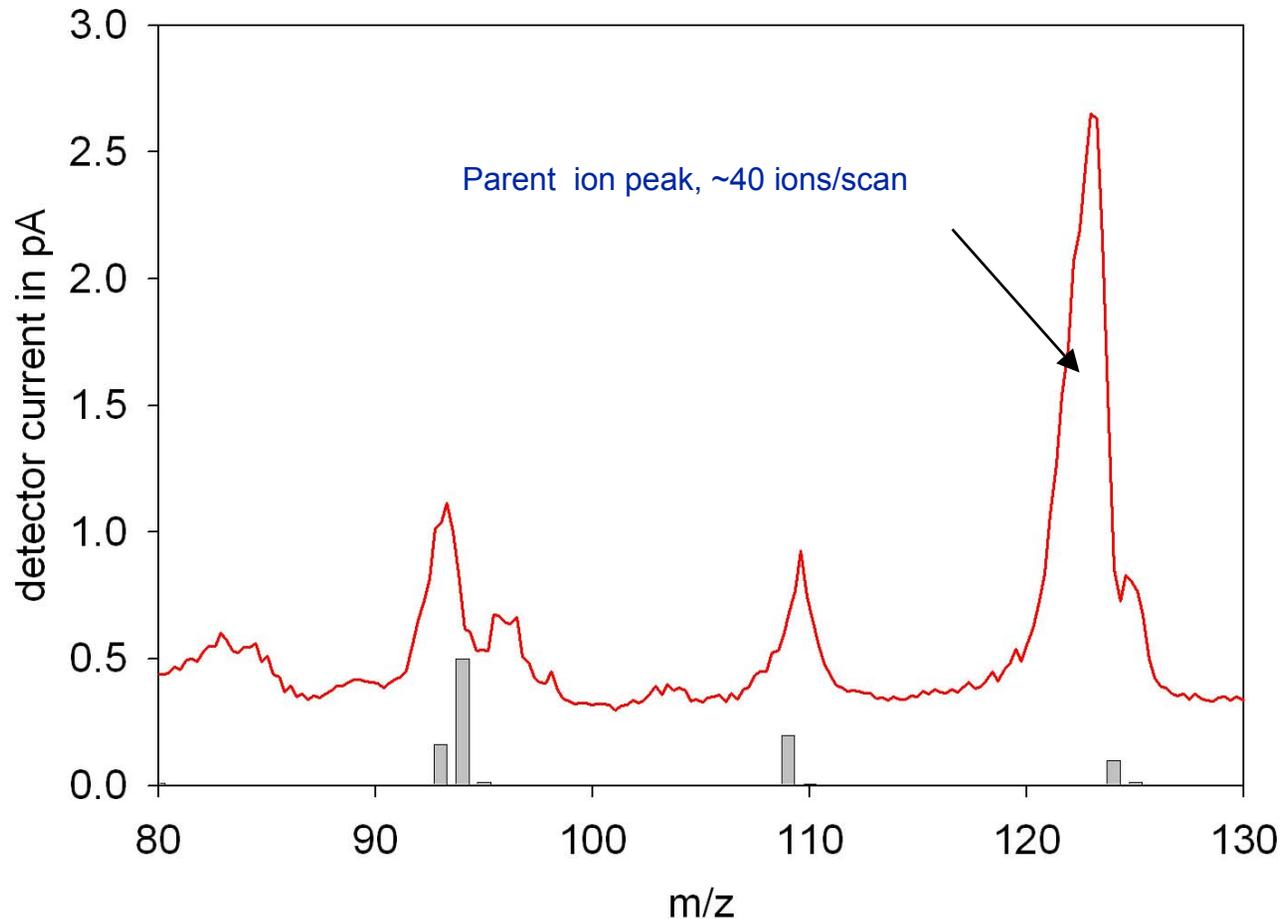


Mass spectrum of xenon isotopes with helium pressure of 0.46 Torr in chamber. Sticks show major Xe isotopes.  
RF frequency - 6.5 MHz  
RF voltage - ~120-140 V 0-p  
Scan rate - ~5 amu/ms ~600 Xe ions detected/scan



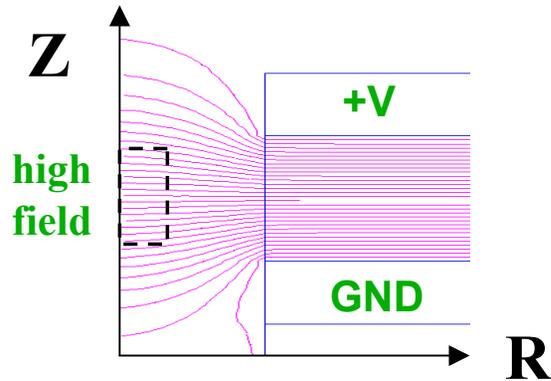
Mass peaks could be observed with chamber pressure as large as 1.7 Torr. Pressure within trap is somewhat lower

# Mass Spectrum of CW Surrogate, DMMP, in a single 1-mm Ion Trap with Chamber at 1.7 Torr

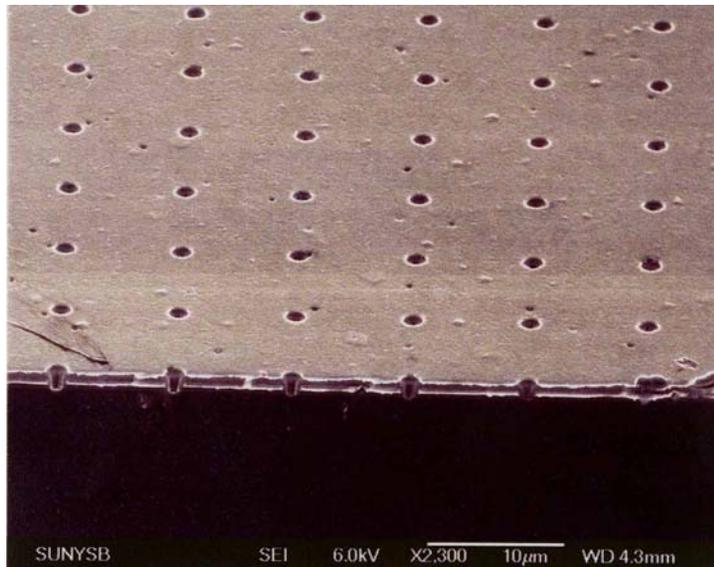


The stick spectrum shows the parent ion and fragment ions resulting from electron-impact ionization of DMMP, furnished by NIST. RF voltage from 80-130 V 0-p.

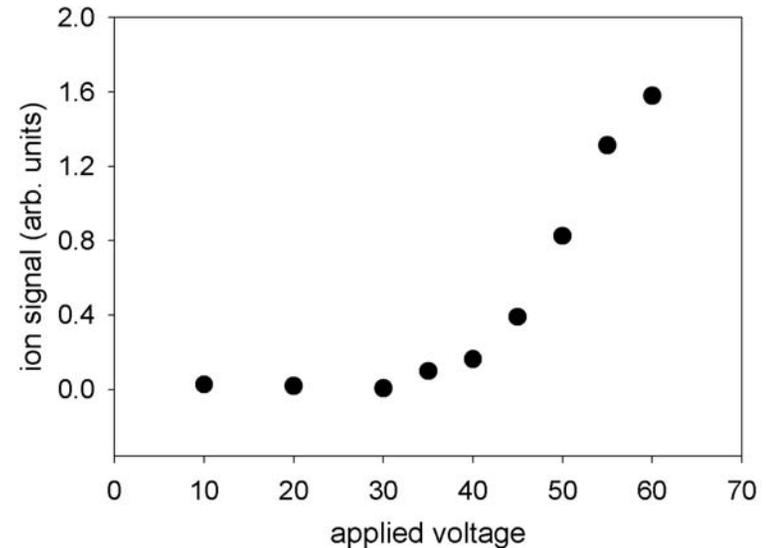
# Soft Ionization Membrane



0.8 and 0.3- $\mu\text{m}$  microfabricated devices from Lucent are being tested at low pressure. We have observed ions being formed when a voltage is applied between the two electrodes.



Soft ionization array, before cavity etch



Ion generation from 0.3  $\mu\text{m}$  membrane

# Summary

- Mass spectrometry with ion traps of submillimeter dimension is feasible
- Mass resolution is comparable to or better than from conventional ion traps
- They operate at lower voltages, higher frequency, and higher pressure
- Arrays of traps can store greater number of ions for higher sensitivity
- All components are amenable to microfabrication

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